ABSTRACT

The present disclosure provides a stage device and a semiconductor process apparatus. The disclosed stage device is configured to bear and drive a front opening unified pod to move outside a loading-unloading chamber of the semiconductor process apparatus in a first direction. The stage device includes a stage support, a bearing portion, a driving mechanism, and a buffer mechanism. The driving mechanism is arranged on the stage support, and the bearing portion is movably arranged on the stage support in the first direction. The driving mechanism is connected to the bearing portion through the buffer mechanism, and configured to drive the bearing portion to move in the first direction through the buffer mechanism. In a case that the driving mechanism drives the bearing portion to move to a connection location in the first direction through the buffer mechanism, the bearing portion continues moving by a preset buffer distance in the first direction under a buffer action of the buffer mechanism. According to the above solution, the problem that when a stage device drives an opening of a front opening unified pod to be connected to a transfer port of a loading-unloading chamber in the related art, insufficient sealing between the opening of the front opening unified pod and the transfer port of the loading-unloading chamber is likely to be caused can be solved.